

Cheng zhen-ying

List of Publications by Year in descending order

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papers

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all docs

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docs citations

15
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85
citing authors

#	ARTICLE	IF	CITATIONS
1	High-precision and low-cost vibration generator for low-frequency calibration system. Measurement Science and Technology, 2018, 29, 034008.	2.6	18
2	Analysis and Comparison of Bayesian Methods for Measurement Uncertainty Evaluation. Mathematical Problems in Engineering, 2018, 2018, 1-10.	1.1	15
3	Uncertainty evaluation for dynamic identification of a micro contact probe based on the signal transmission chain analysis method. Measurement Science and Technology, 2020, 31, 125007.	2.6	9
4	New Radius and Roundness Measurement for Microspheres Using a High-Precision Run-Out Error Separation Method. IEEE Transactions on Instrumentation and Measurement, 2022, 71, 1-10.	4.7	6
5	Modeling and Optimal Design for a High Stability 2D Optoelectronic Angle Sensor. Sensors, 2019, 19, 4409.	3.8	5
6	A Low-Frequency Micro Accelerometer Based on Three-Lobed Leaf Spring and a Focus Probe. IEEE Photonics Journal, 2019, 11, 1-12.	2.0	5
7	A simple asymptotic search method for estimation of minimum zone sphericity error. AIP Advances, 2020, 10, 015322.	1.3	5
8	Novel Compensation Method of Volumetric Errors for Micro-Coordinate Measuring Machines Using Abbe and Bryan Principles. IEEE Transactions on Instrumentation and Measurement, 2022, 71, 1-10.	4.7	5
9	Modeling and improvement of a low-frequency micro-accelerometer. Review of Scientific Instruments, 2021, 92, 025002.	1.3	4
10	Analog Electronic Method for Solving Nonlinear Errors of Sinusoidal Waves in Interferometry. IEEE Transactions on Instrumentation and Measurement, 2021, 70, 1-10.	4.7	4
11	Drift Reduction of a 4-DOF Measurement System Caused by Unstable Air Refractive Index. Sensors, 2020, 20, 6329.	3.8	3
12	Self-Calibration Vision Method and System for Automatically Moving CMM Stylus Into Micro Holes. IEEE Sensors Journal, 2022, 22, 3579-3584.	4.7	3
13	Development of a High-Precision Optical Force Sensor With $\frac{1}{4}$ N-Level Resolution. IEEE Sensors Journal, 2022, 22, 12738-12745.	4.7	3
14	Correction to "Analog Electronic Method for Solving Nonlinear Errors of Sinusoidal Waves in Interferometry". IEEE Transactions on Instrumentation and Measurement, 2021, 70, 1-1.	4.7	2
15	Uniform Accuracy Lifetime Principle and Optimal Design Methods for Measurement Systems. Applied Sciences (Switzerland), 2022, 12, 3961.	2.5	0